Atty Docket: 10829-8718US <u>Inventors</u>: Kevin L. Beaman et al. <u>Title</u>: METHODS AND SYSTEMS FOR CONTROLLING TEMERATURE DURING MICROFEATURE WORKPIECE PROCESSING, E.G., CVD DEPOSITION

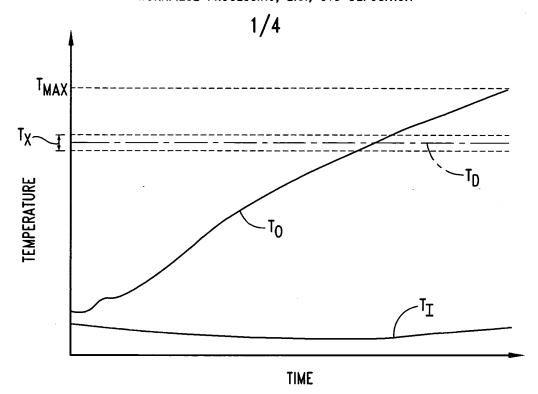


Fig. 1

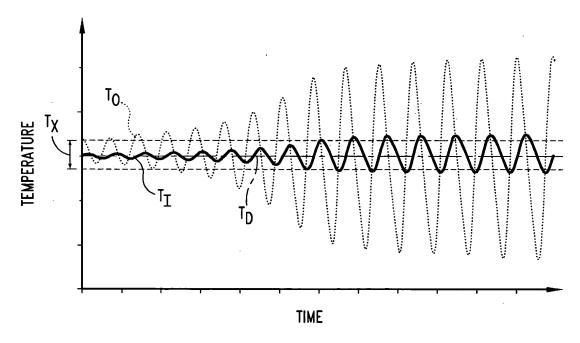


Fig. 2

Atty Docket: 10829-8718US Inventors: Kevin L. Beaman et al.

Title: METHODS AND SYSTEMS FOR CONTROLLING TEMERATURE DURING MICROFEATURE

WORKPIECE PROCESSING, E.G., CVD DEPOSITION

2/4

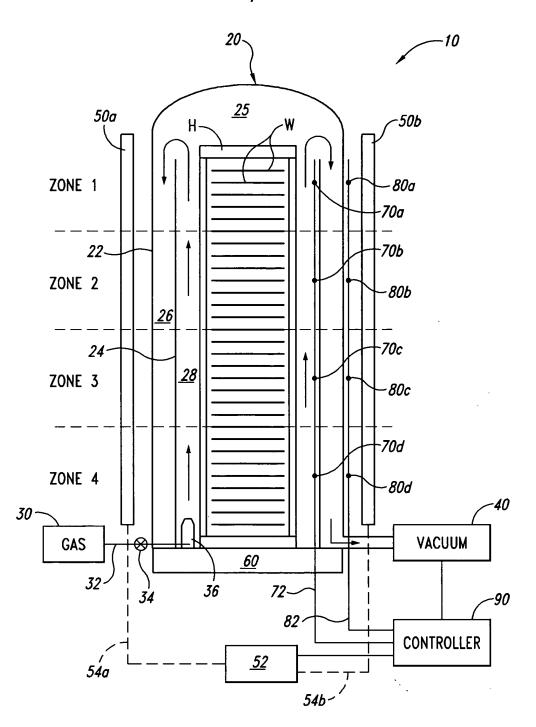
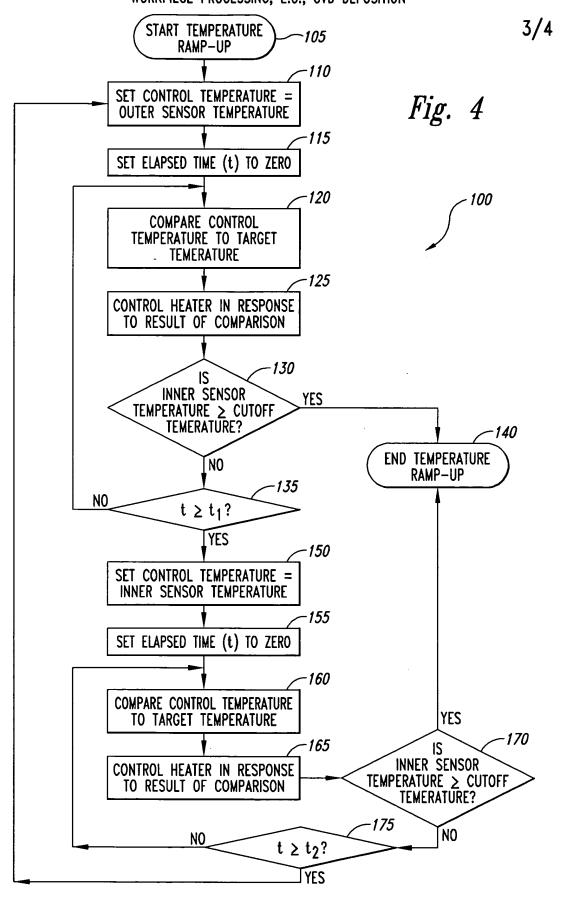


Fig. 3



Atty Docket: 10829-8718US <u>Inventors</u>: Kevin L. Beaman et al. <u>Title</u>: METHODS AND SYSTEMS FOR CONTROLLING TEMERATURE DURING MICROFEATURE WORKPIECE PROCESSING, E.G., CVD DEPOSITION

4/4

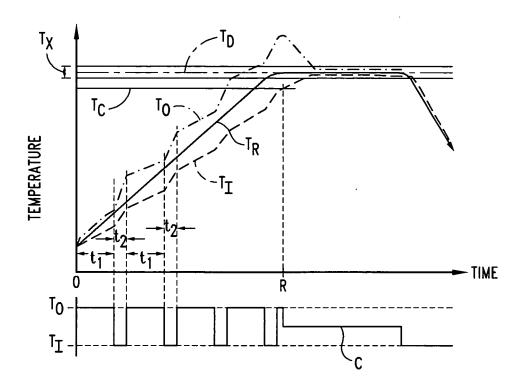


Fig. 5